

Title (en)

A carrier head with a layer of conformable material for a chemical mechanical polishing system

Title (de)

Trägervorrichtung mit einer Lage anpassbarem Material für ein chemisch-mechanisches Poliersystem

Title (fr)

Dispositif de support comprenant une couche de matière conformable pour un système de polissage mécano-chimique

Publication

EP 0835723 A1 19980415 (EN)

Application

EP 97308022 A 19971010

Priority

- US 72868896 A 19961010
- US 72929896 A 19961010

Abstract (en)

The disclosure relates to a carrier head (100) for a chemical mechanical polishing apparatus. A layer of conformable material (308) is disposed in a recess of the carrier head to provide a mounting surface for a substrate (10). The conformable material may be elastic and undergo normal strain in response to an applied load. The carrier head may also include a support fixture (352) detachably connected to a backing fixture (350), a retaining ring (362) connected directly to the conformable material, and a shield ring (360) which projects over a portion of the layer of conformable material.
<IMAGE> <IMAGE>

IPC 1-7

B24B 37/04

IPC 8 full level

B24B 37/04 (2006.01); **H01L 21/304** (2006.01)

CPC (source: EP)

B24B 37/042 (2013.01); **B24B 37/30** (2013.01)

Citation (search report)

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